

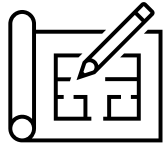


# 3D-Druck von Master- Templates für die Mikrooptik und Mikrofluidik

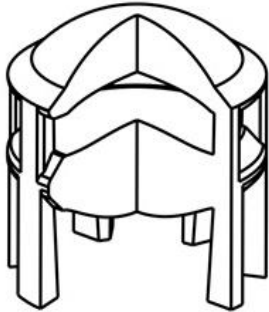
Dr. Jochen Zimmer, Sales Manager  
Nanoscribe GmbH & Co. KG

Coffee Lectures 2022/2023: Polymers for the Future  
25. Januar 2023: Smarte Prozesse: Aktivierung und Mikroproduktion

# We build 3D microfabrication systems

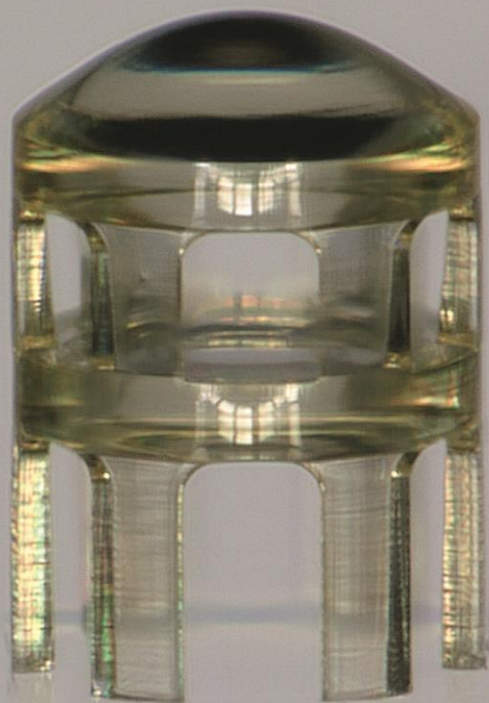


Design file



Microstructure





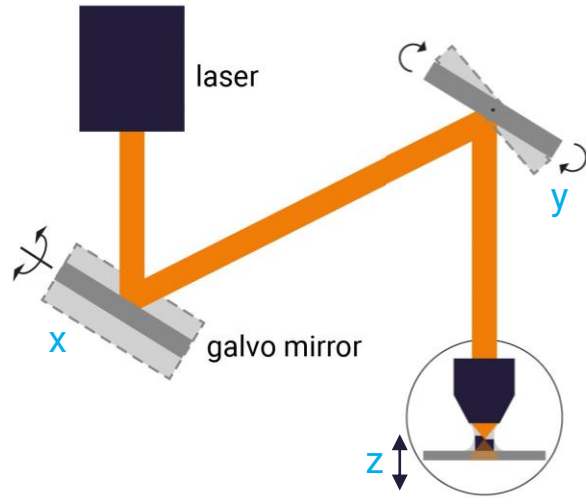
100  $\mu\text{m}$

# Nanoscribe **worldwide** in figures



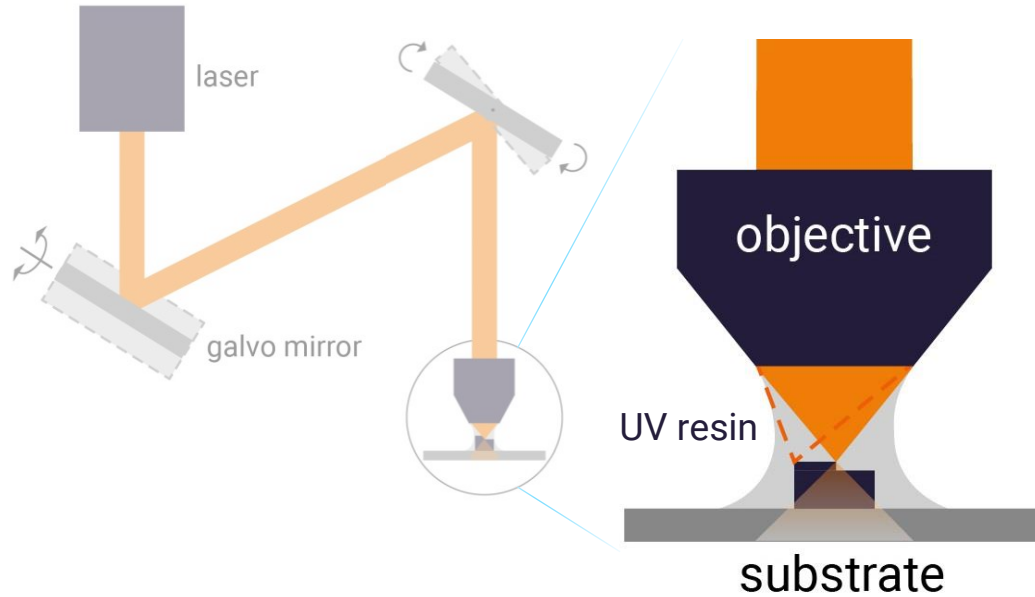
# Technology basics

## Galvo scanners for highest print speed



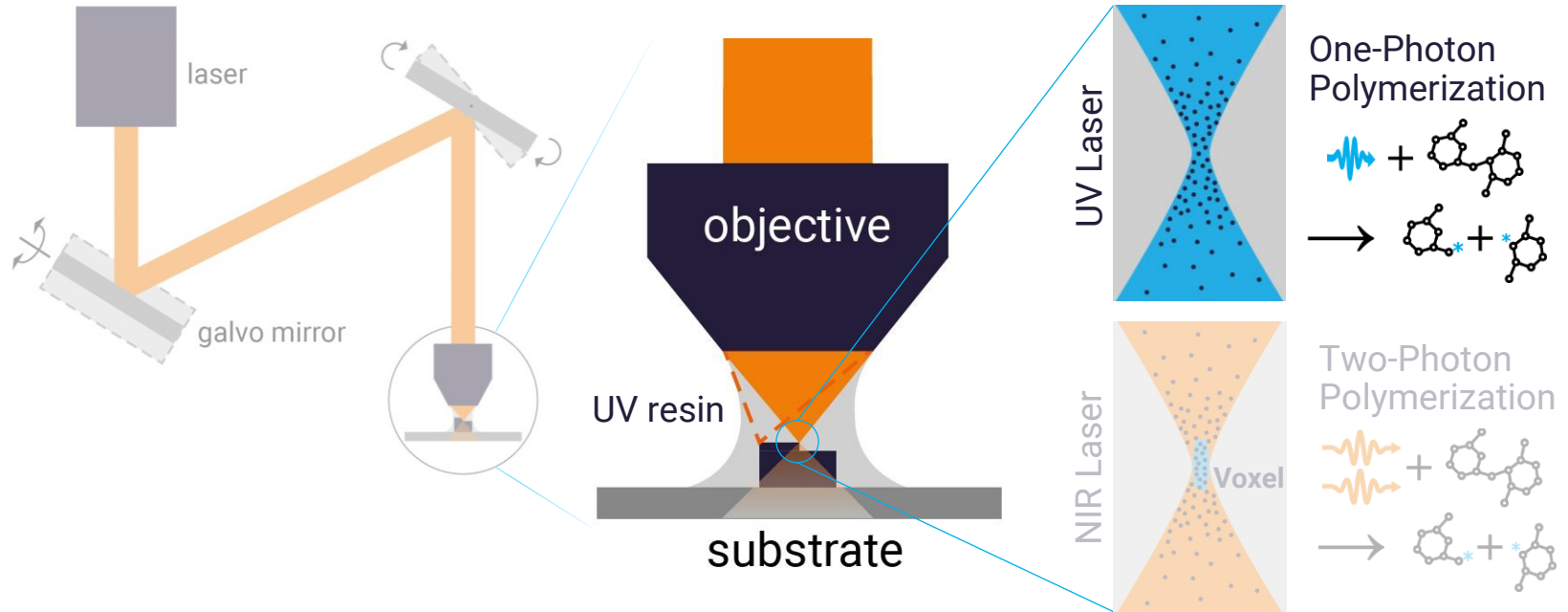
# Technology basics

## Dip-in Laser Lithography (DiLL)



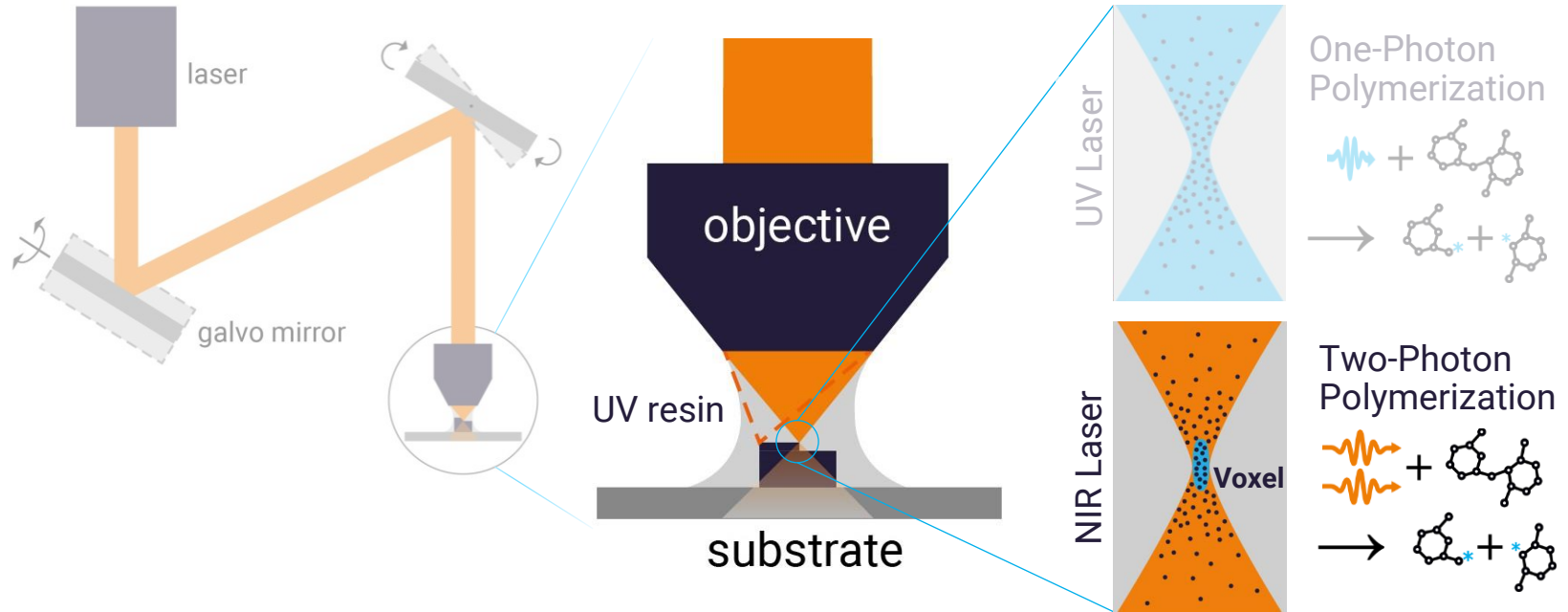
# Technology basics

## Two-Photon Polymerization (2PP)



# Technology basics

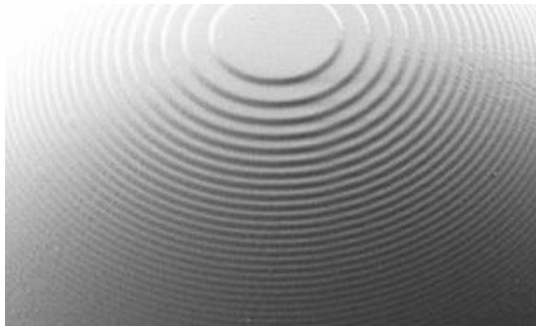
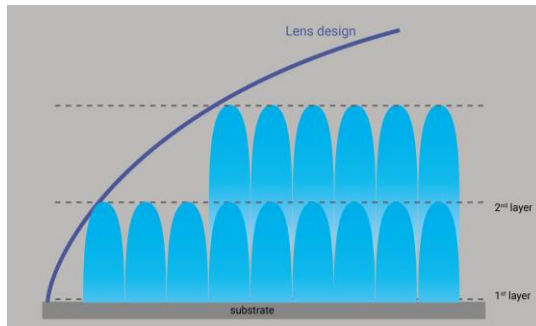
## Two-Photon Polymerization (2PP)





# Challenge in high-precision 3D printing

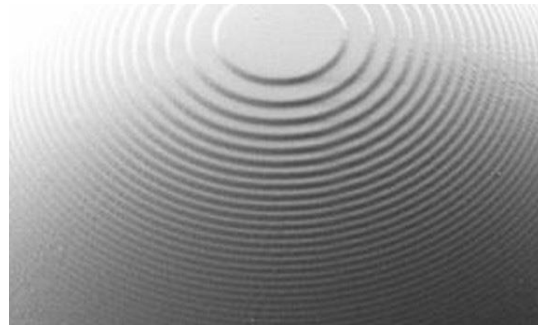
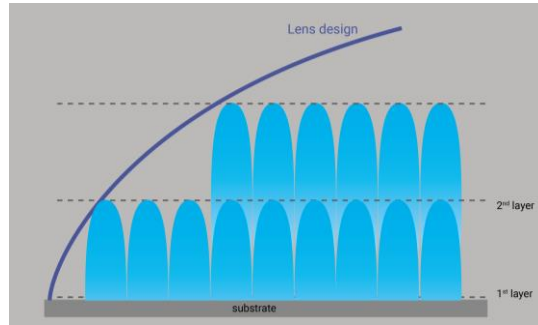
## Staircasing vs. printing speed



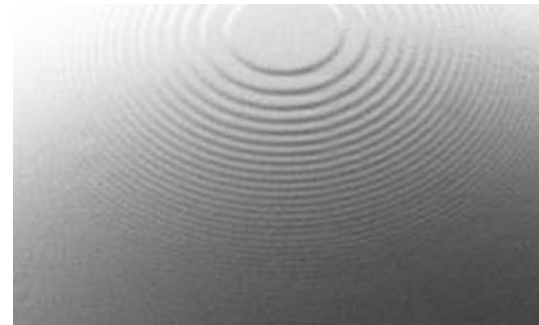
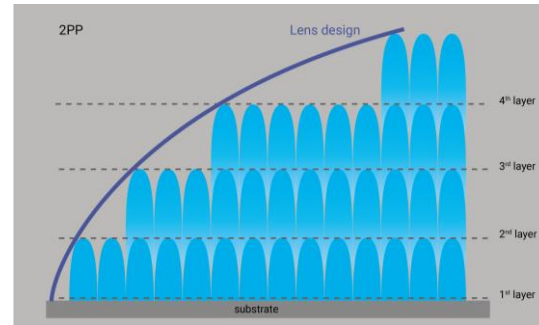
Slicing distance  $2\ \mu\text{m}$

# Challenge in high-precision 3D printing

## Staircasing vs. printing speed



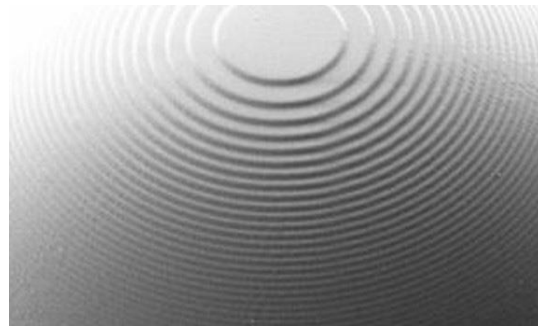
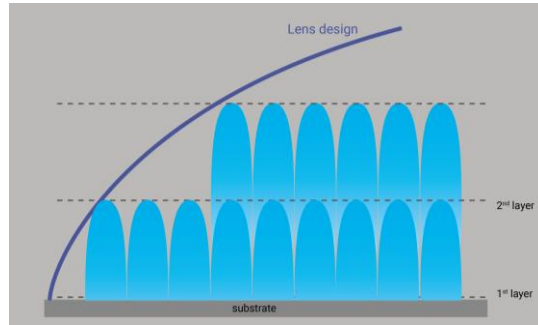
Slicing distance 2  $\mu\text{m}$



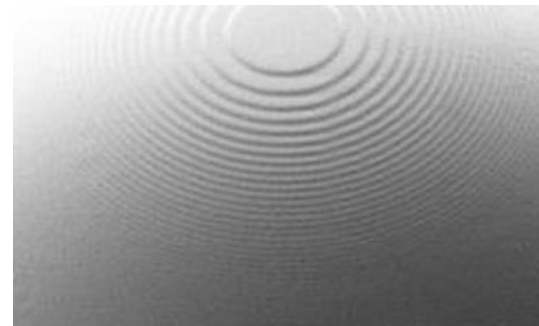
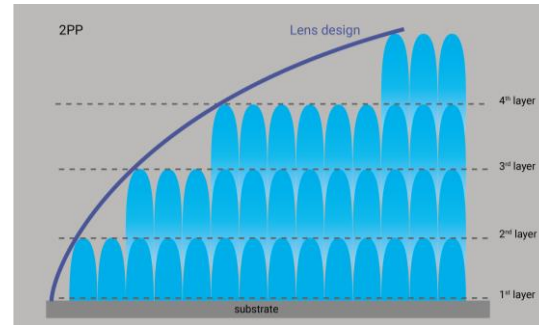
Slicing distance 1  $\mu\text{m}$

# Challenge in high-precision 3D printing

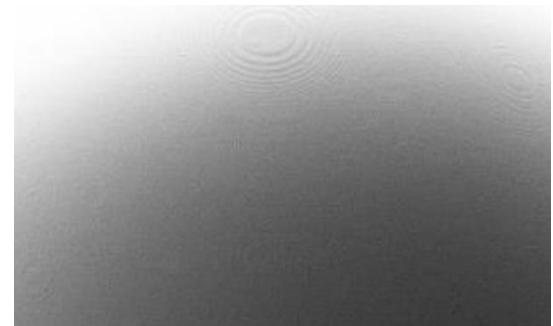
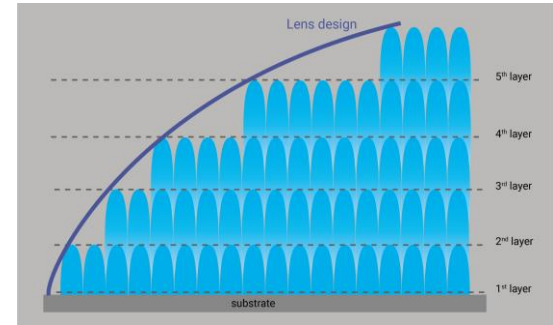
## Staircasing vs. printing speed



Slicing distance 2  $\mu\text{m}$



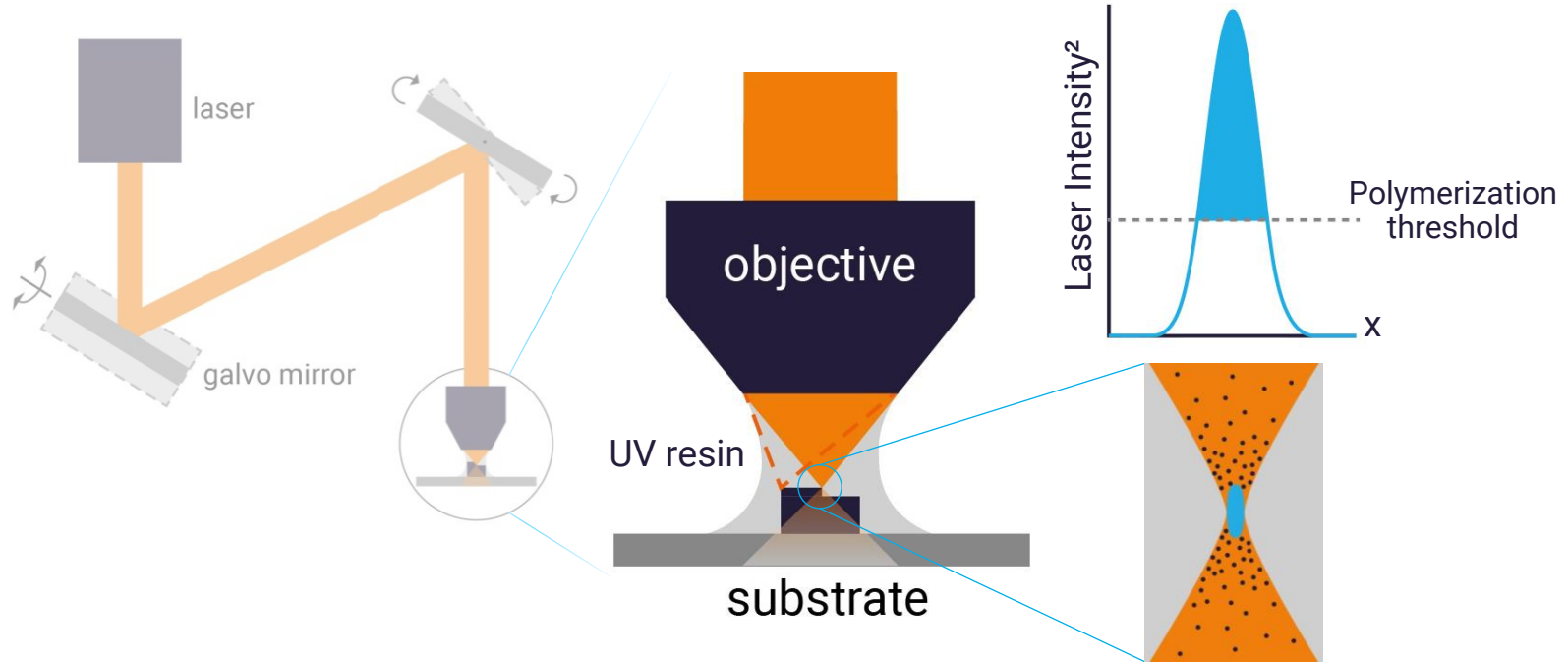
Slicing distance 1  $\mu\text{m}$



Slicing distance 0.6  $\mu\text{m}$

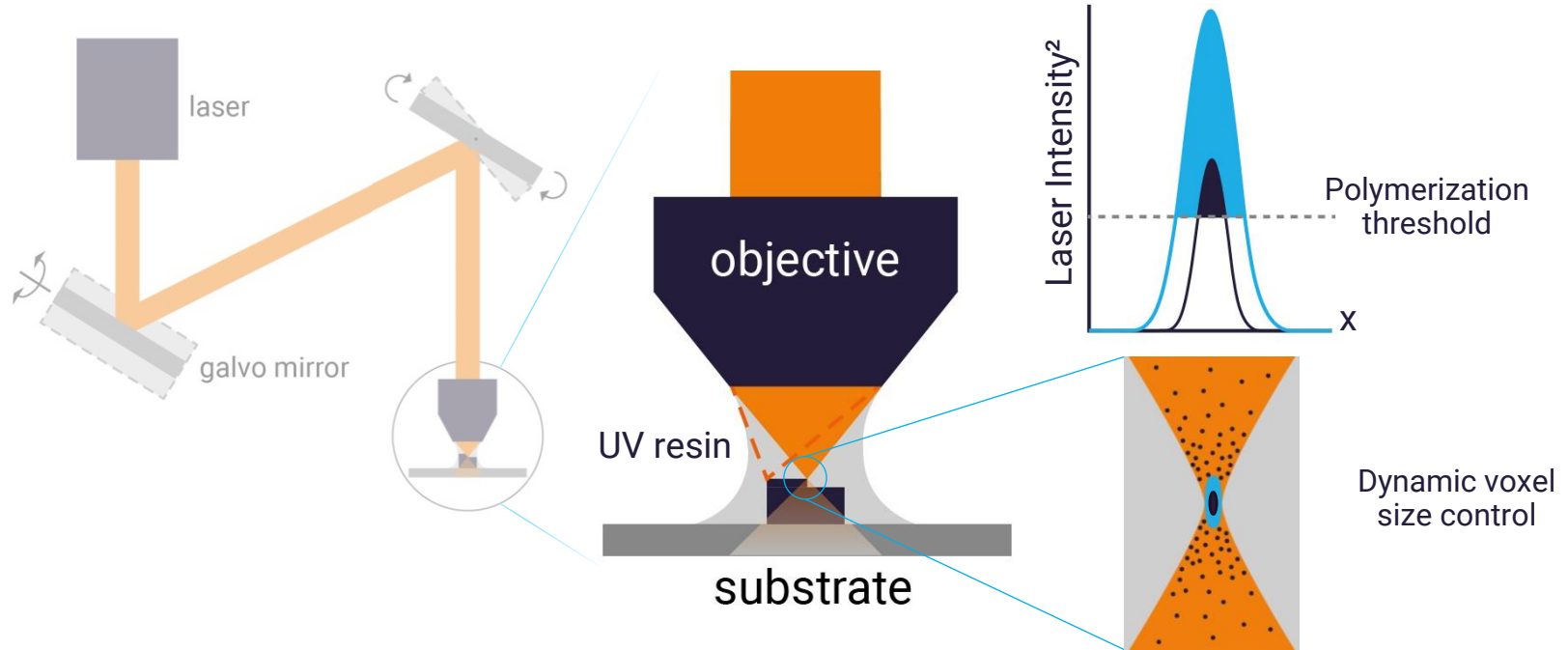
# Technology basics

## Two-Photon Grayscale Lithography (2GL<sup>®</sup>)



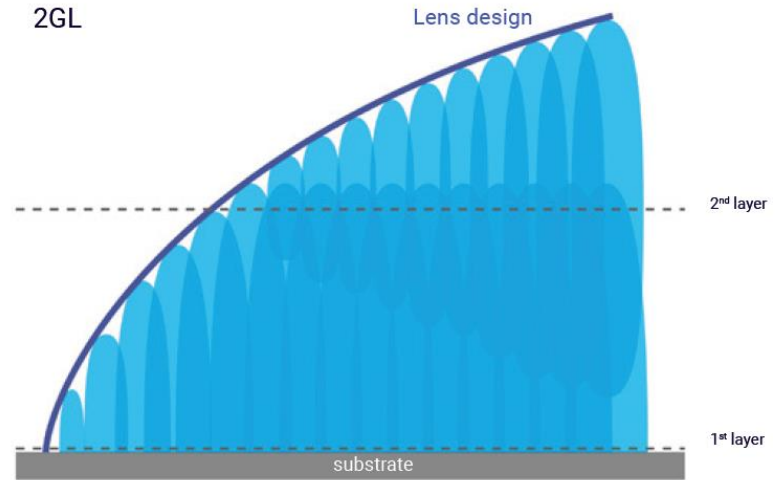
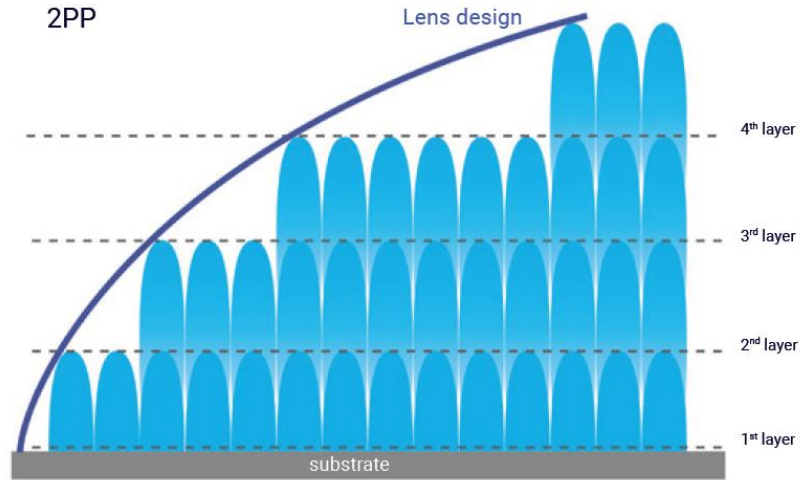
# Technology basics

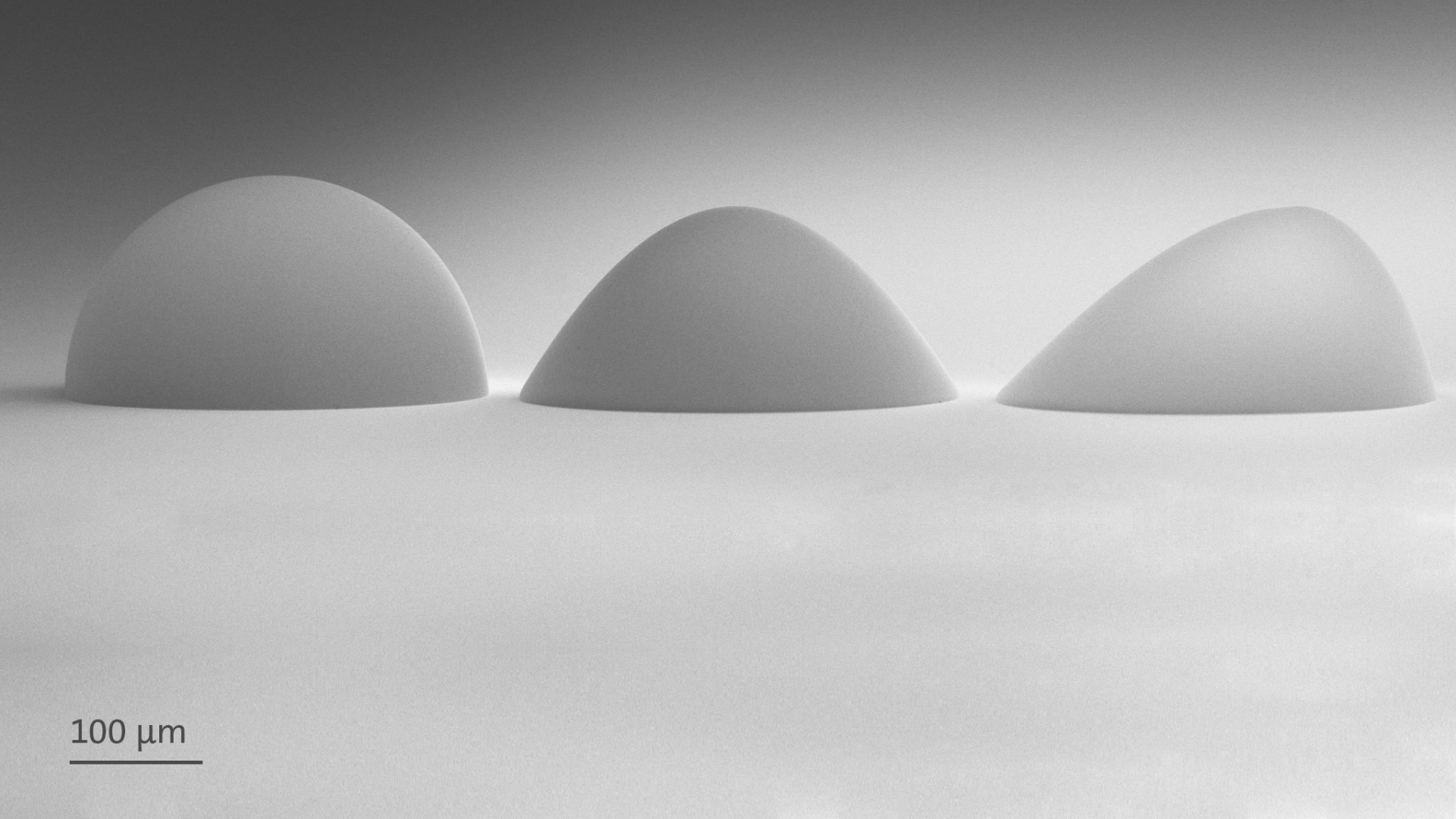
## Two-Photon Grayscale Lithography (2GL®)



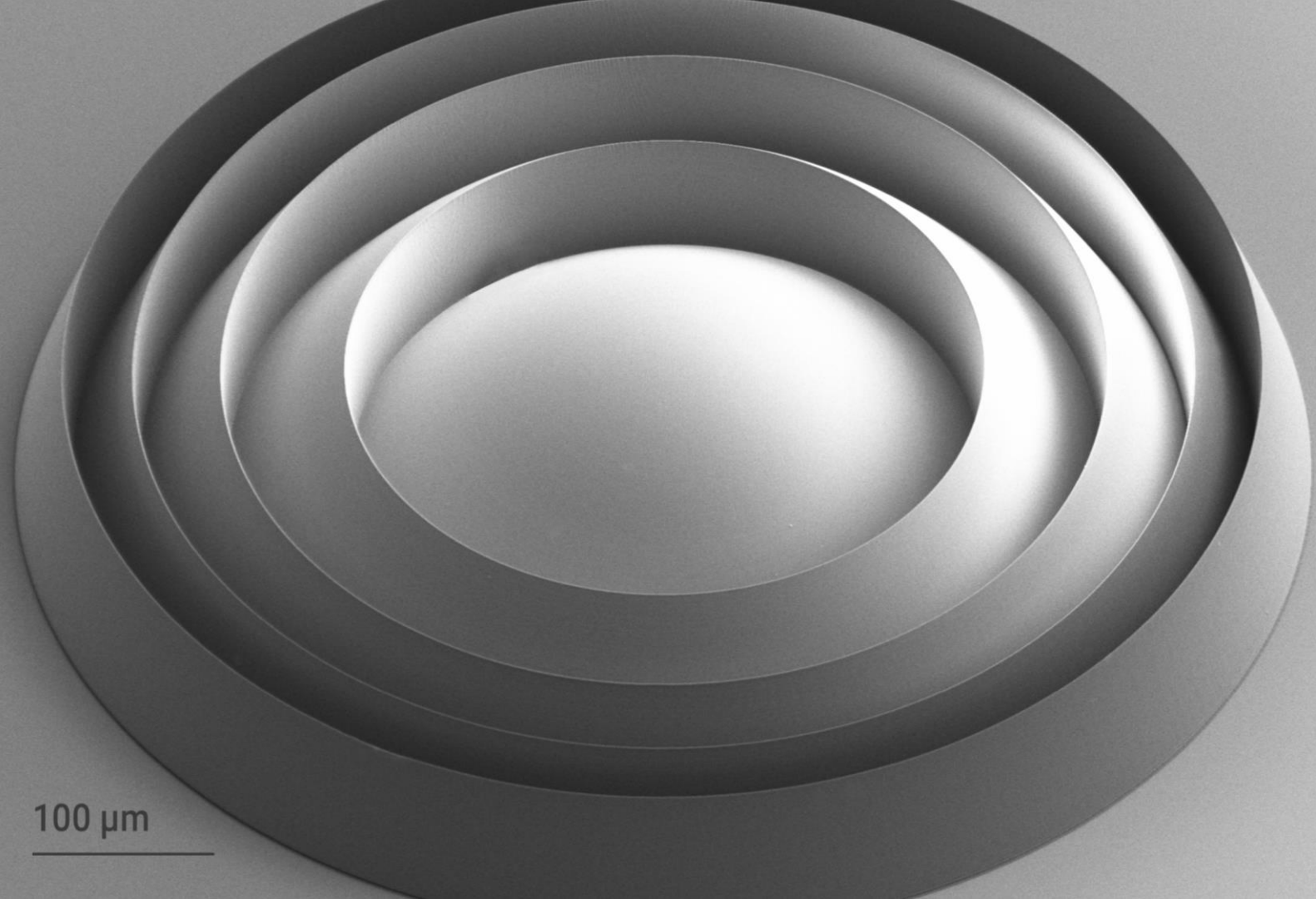
# Challenge in 3D printing

## Staircasing vs. printing speed



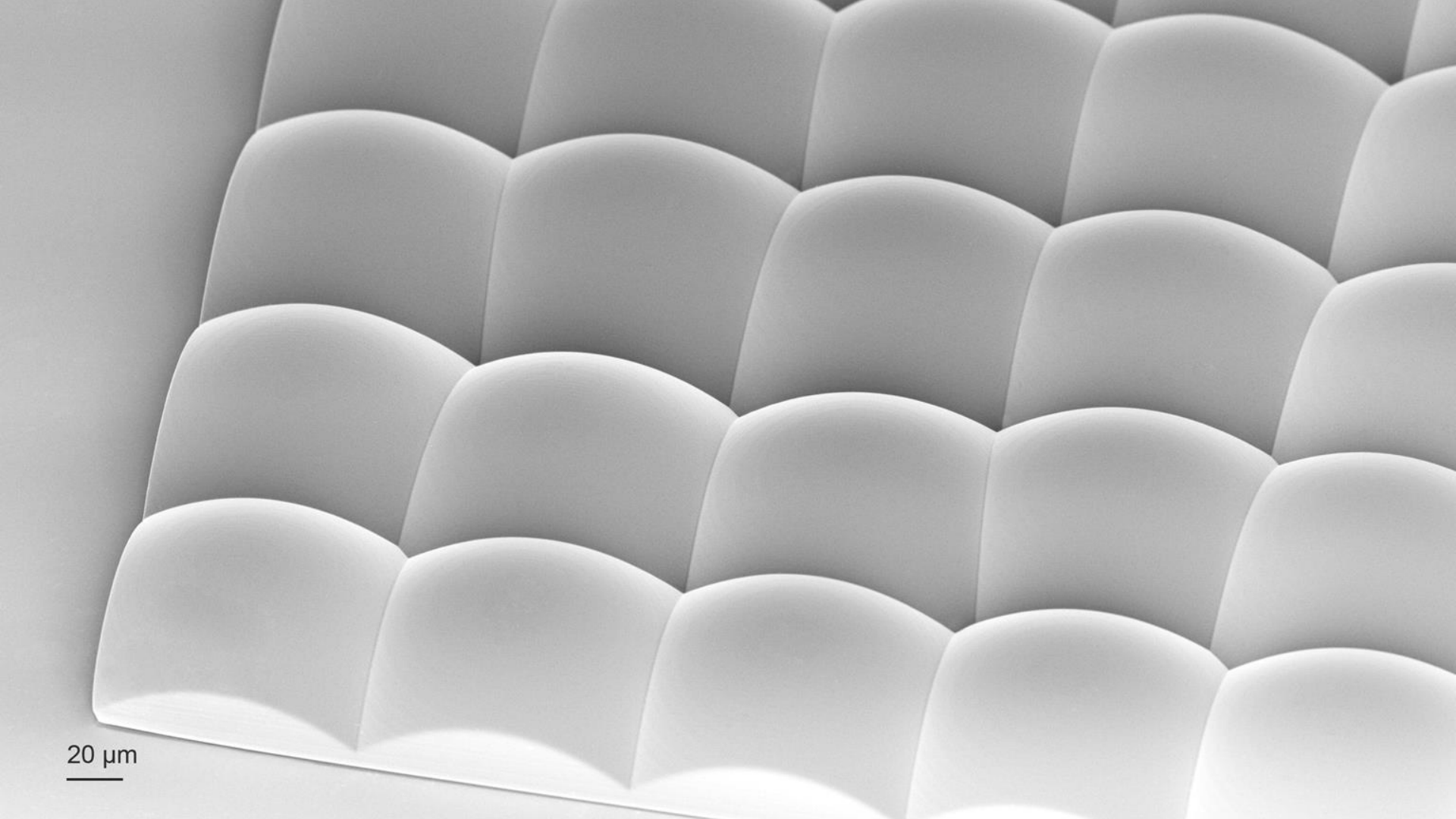


100  $\mu\text{m}$



100  $\mu\text{m}$

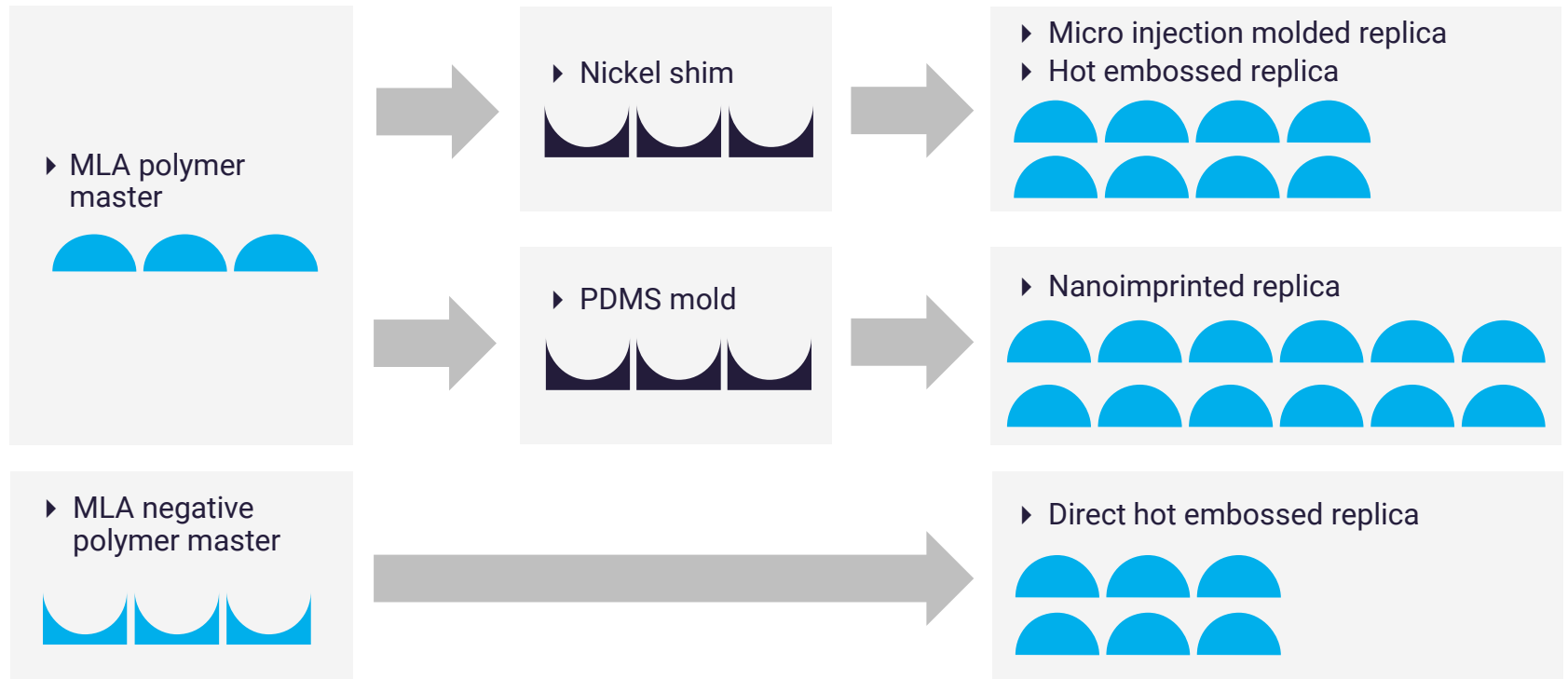




20  $\mu\text{m}$

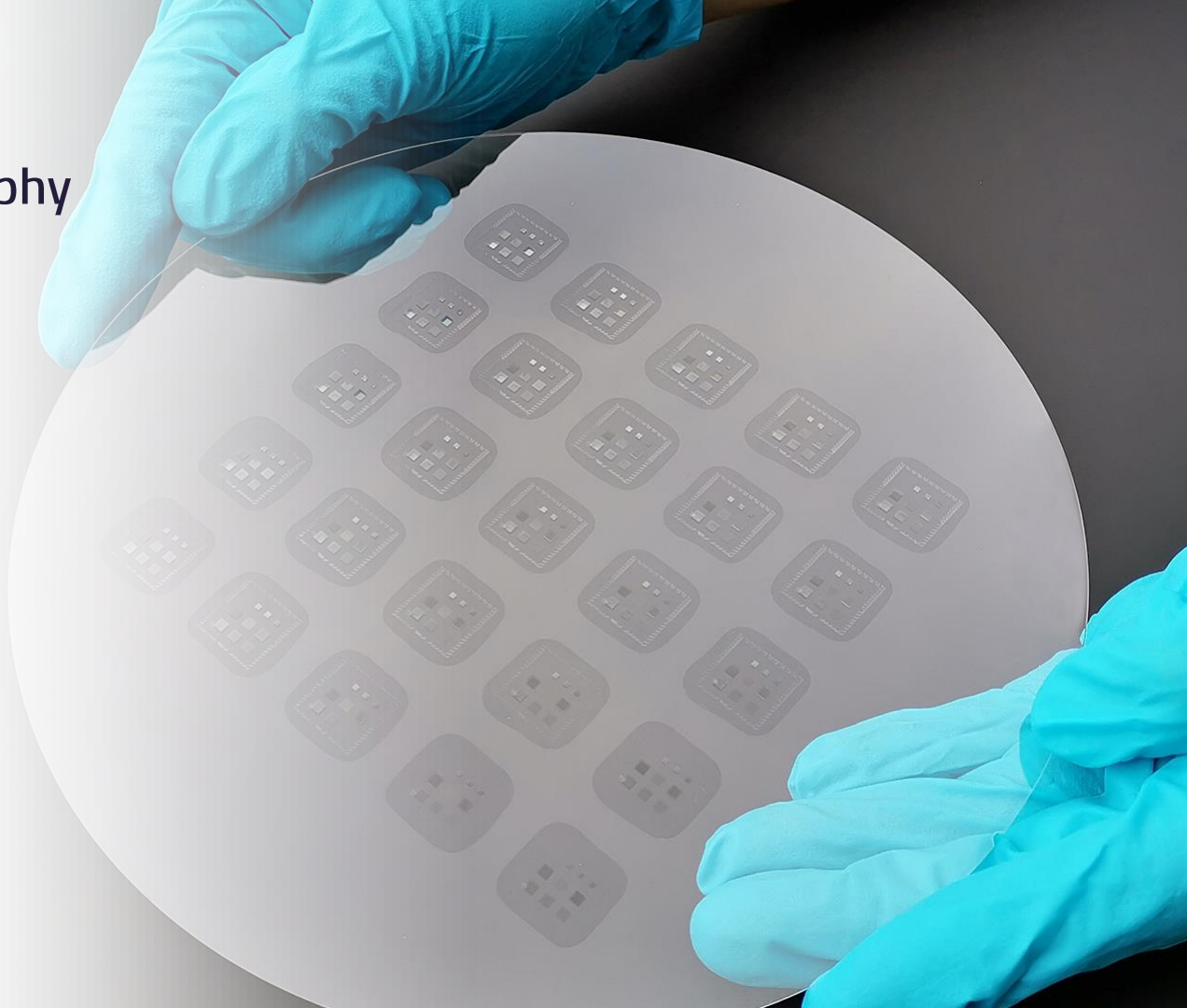
# Replication processes

## From polymer master to small series production



## Replication processes Nanoimprint Lithography

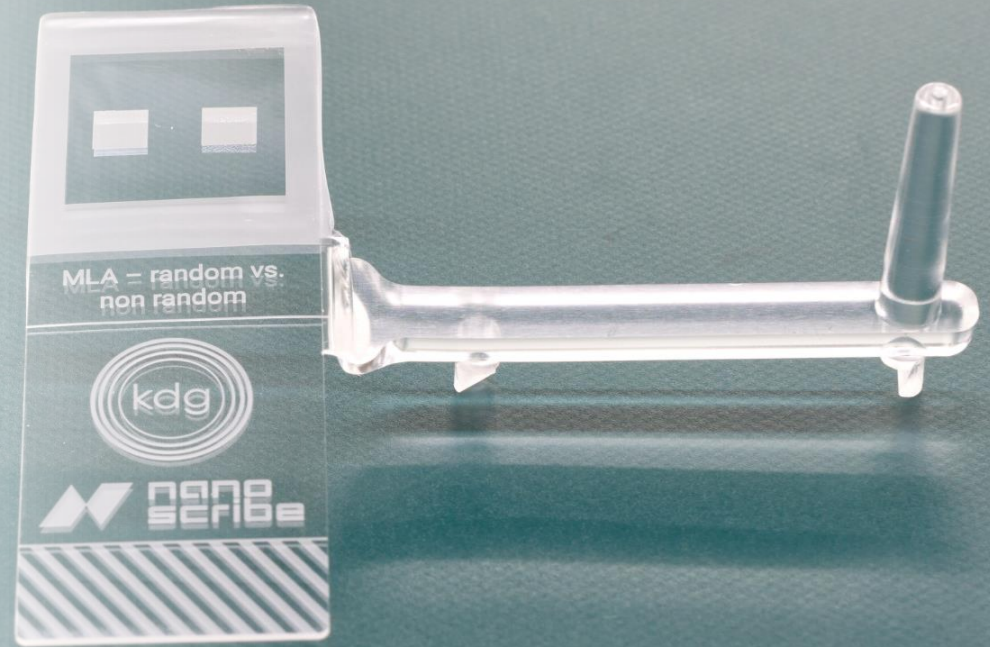
- ▶ 8" wafer
- ▶ Nanoimprint replica
- ▶ Produced by our partner EV Group



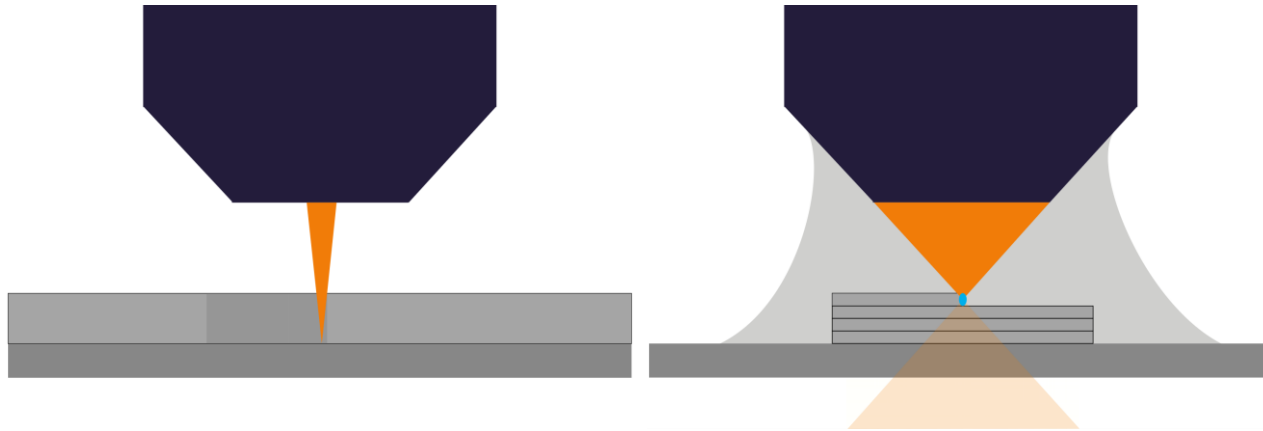
## Replication processes

### Injection Molding

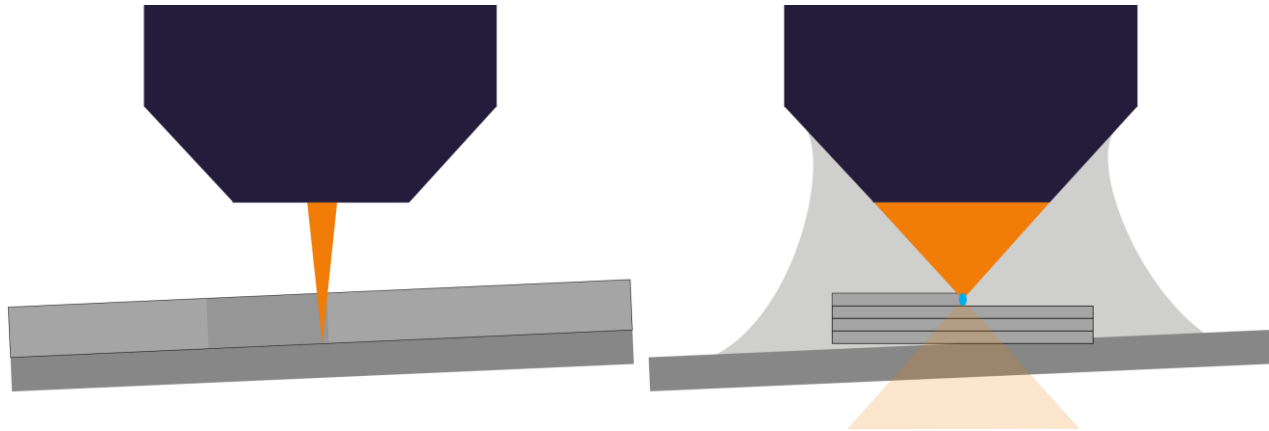
- ▶ Beam homogenizer
- ▶ Injection molded replica
- ▶ Sprue and runner still attached
- ▶ Produced by our partner kdg



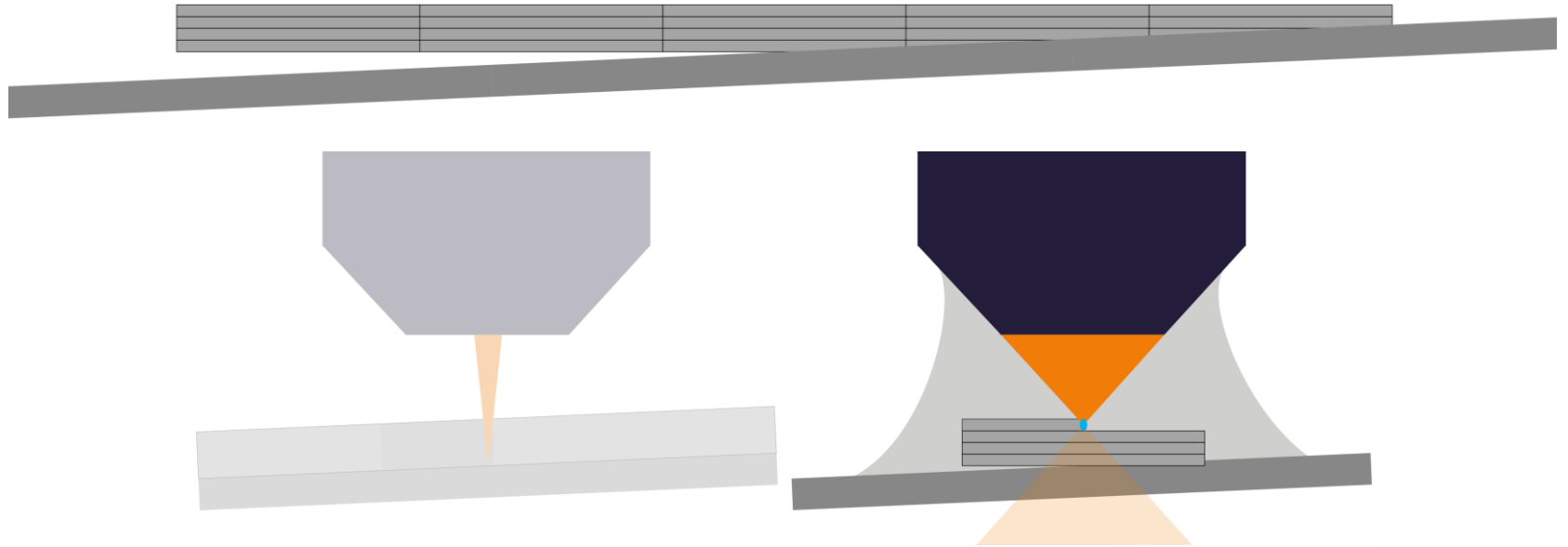
## 2D direct laser writing vs. 3D additive microfabrication



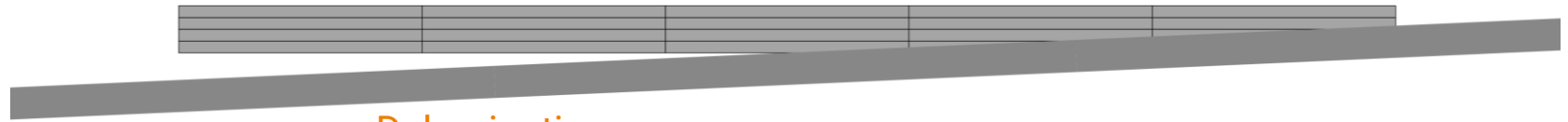
# Sensitivity to minute substrate tilts



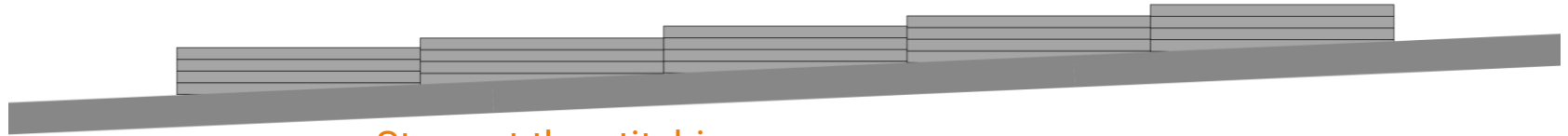
# Large area fabrication on tilted substrates



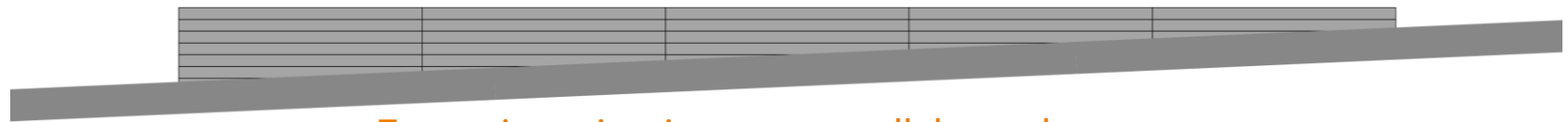
# Large area fabrication on tilted substrates



- ▶ Delamination



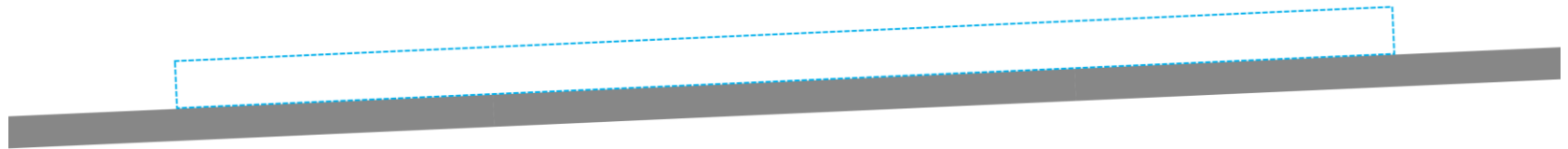
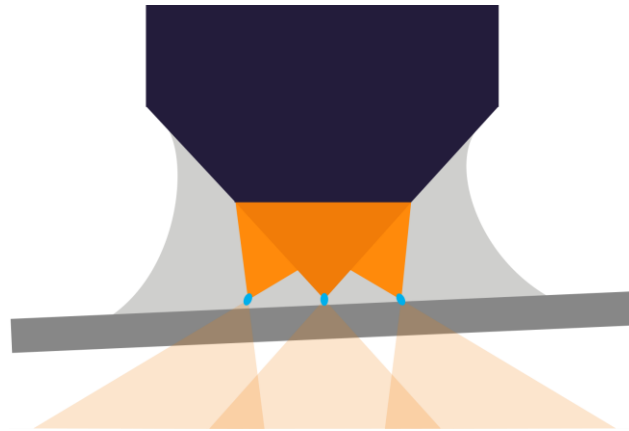
- ▶ Steps at the stitching seams



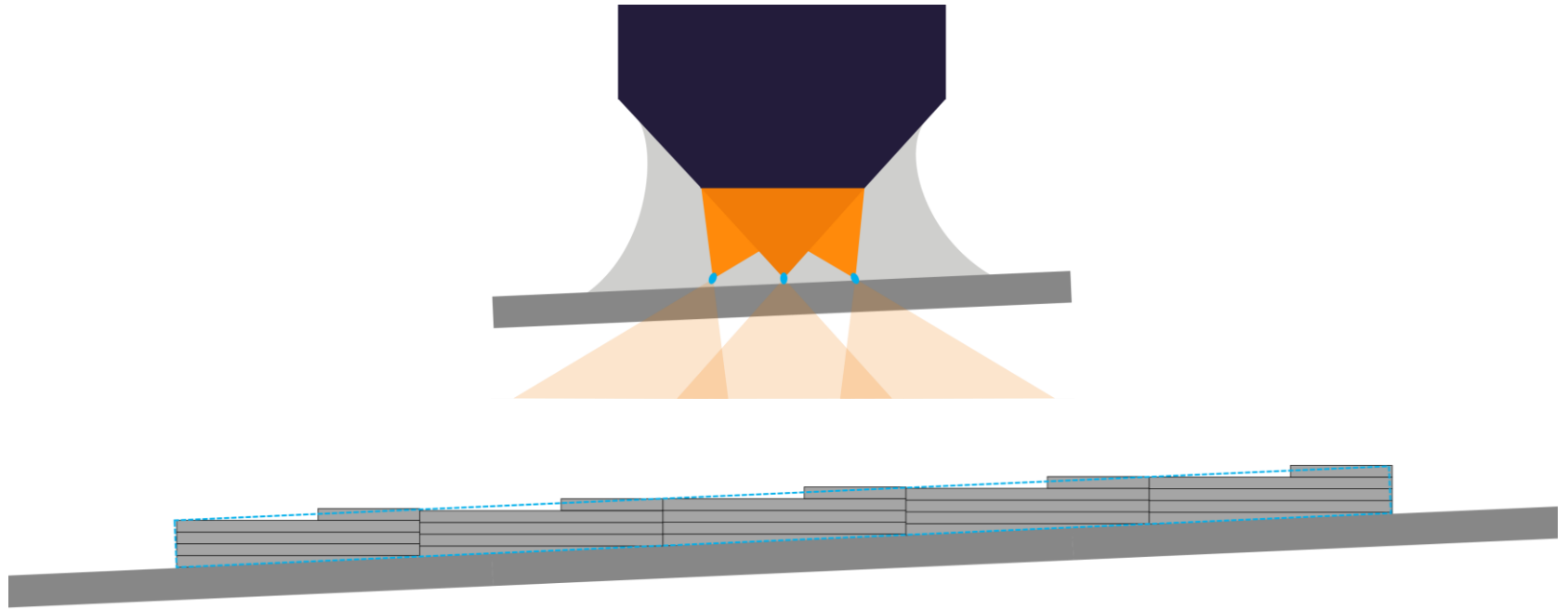
- ▶ Excessive print time, not parallel to substrate



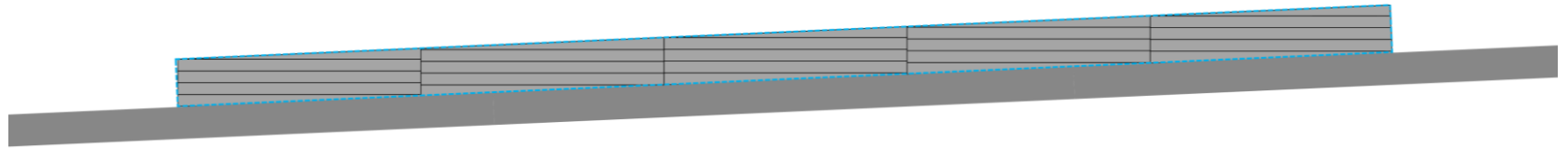
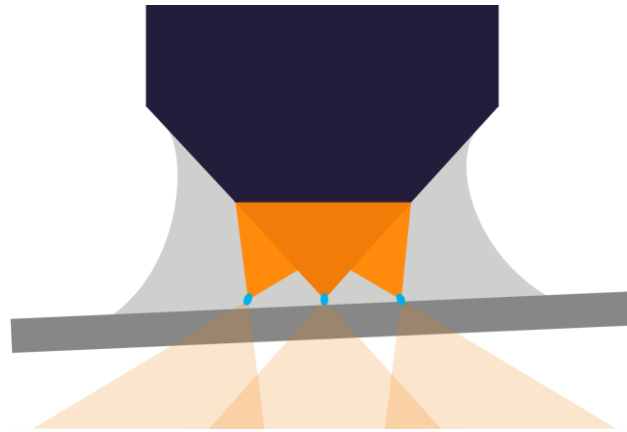
# Measure tilt and rotate design



# Measure tilt and rotate design with conventional slicing



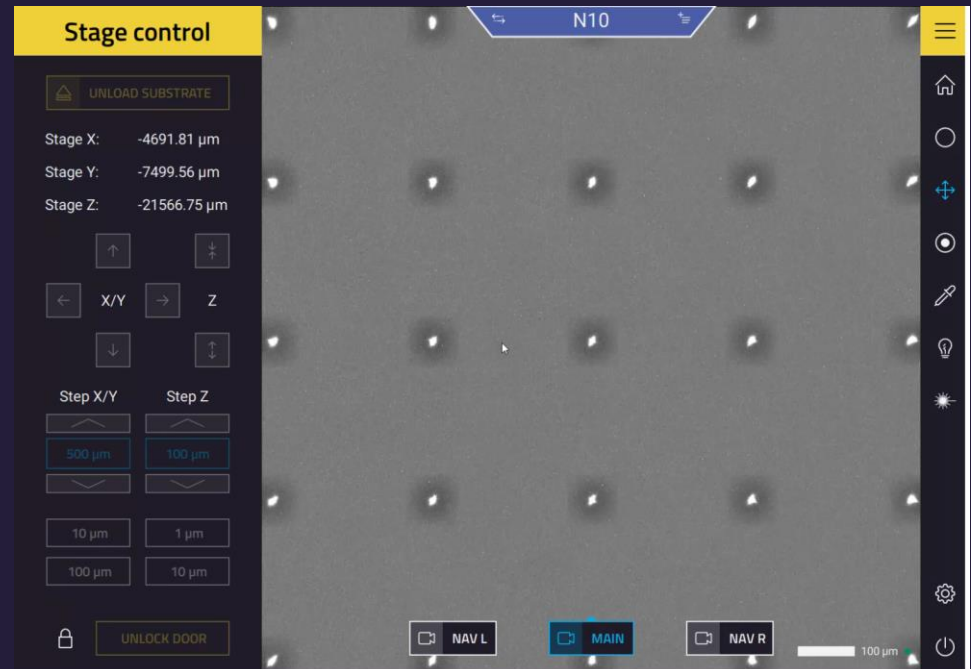
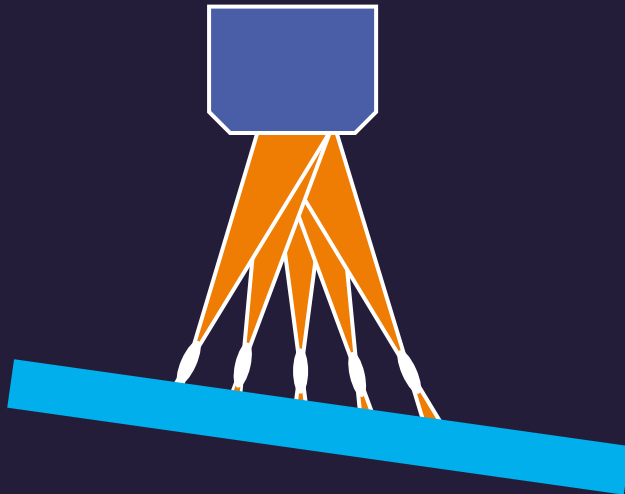
# Measure tilt and rotate design with 2GL



# Printing on wafer: Printing process



## ► Tilt measurement

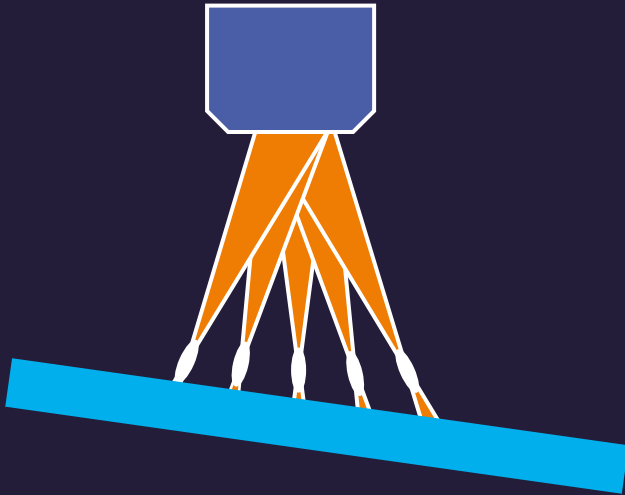


PCT/EP2022/052687 patent pending

# Printing on wafer: Printing process



## ▶ Tilt measurement

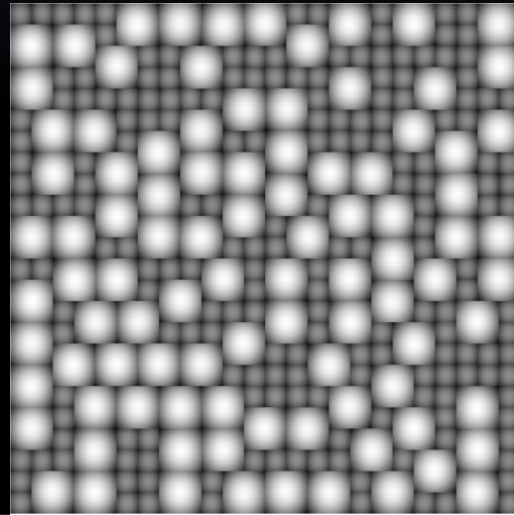


# Refractive beam diffuser based on random MLA

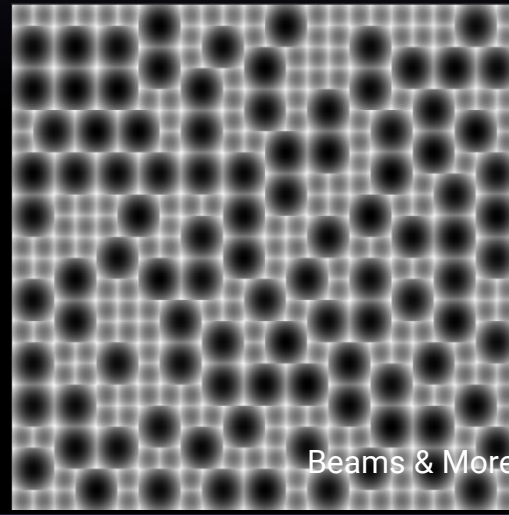


- Design files exported to grayscale 16-bit PNG images with a pixel size of 200nm
- Base unit 1.8 mm wide was repeated in a 3x3 array to create a 5.4 mm diffuser.

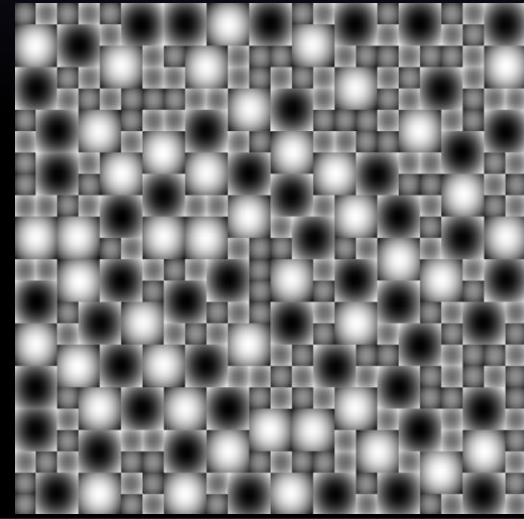
Convex (standard)



Concave 1.8 mm (base unit)



Mixed



56  $\mu\text{m}$

Height

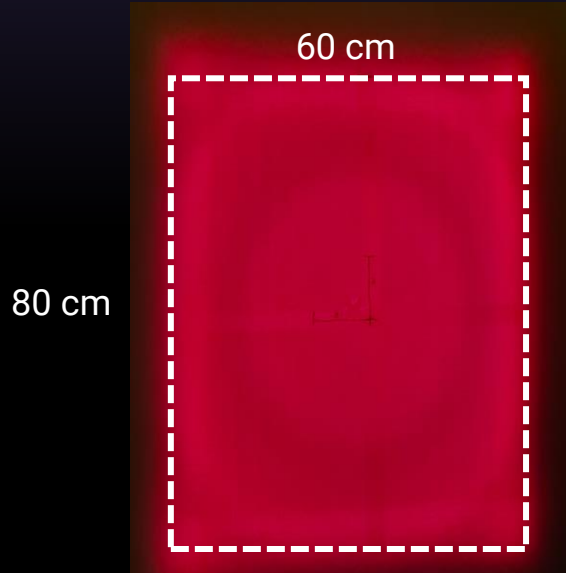
0  $\mu\text{m}$

# Refractive beam diffuser based on random MLA

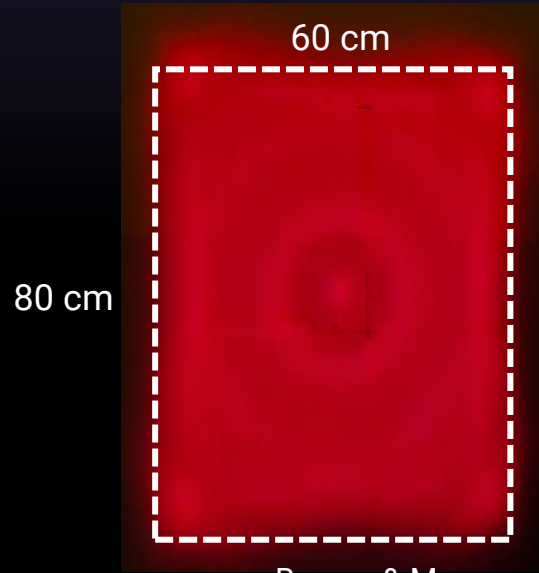


- Experimental results

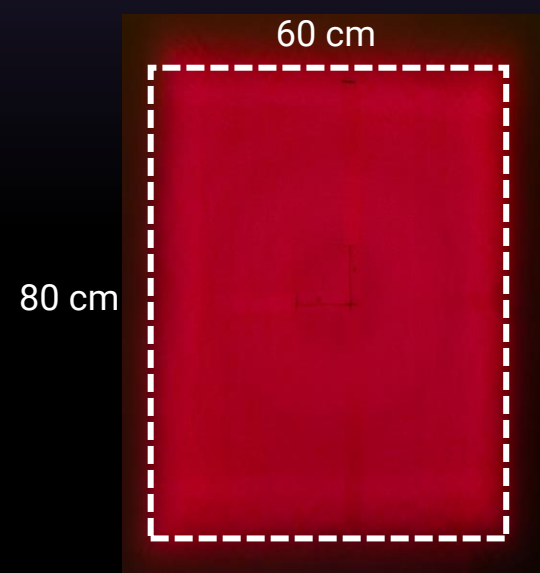
Convex (standard)



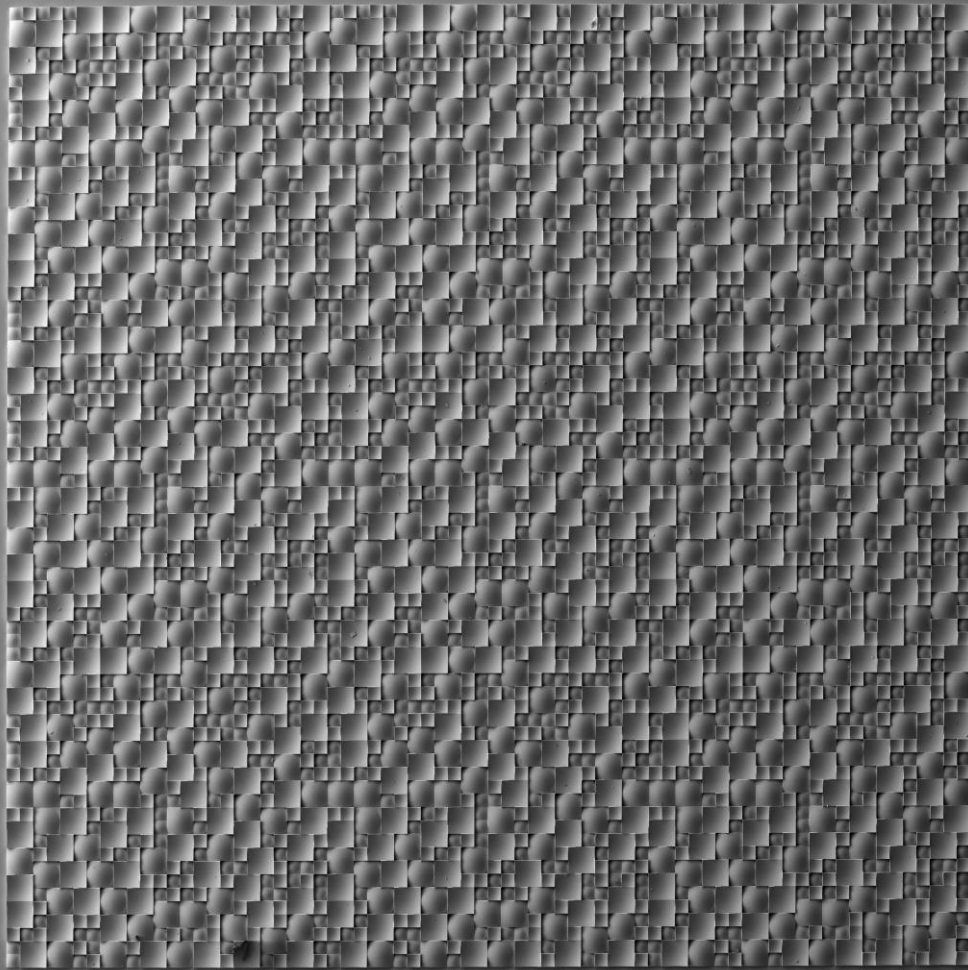
Concave



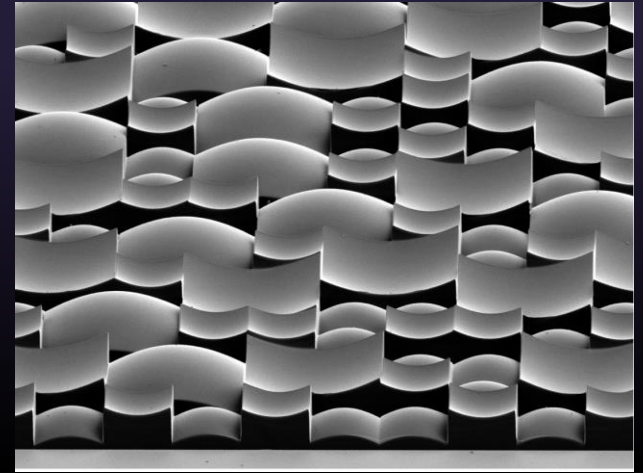
Mixed



Tilt corrected sample



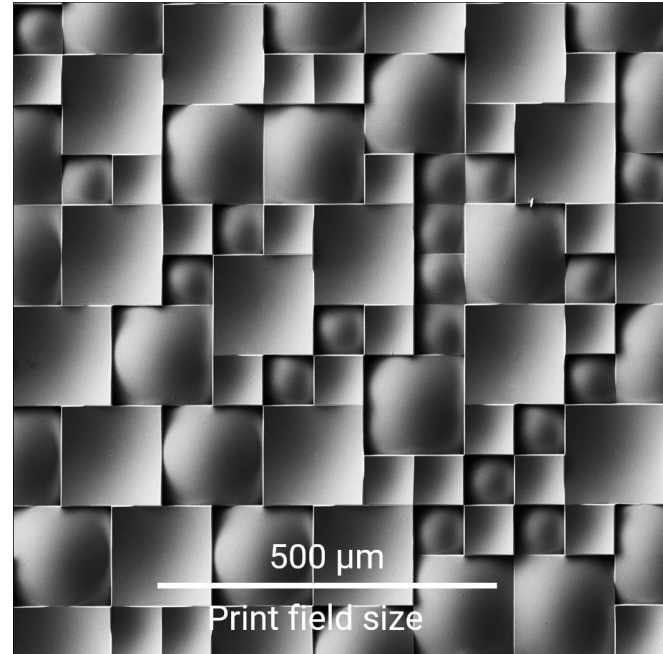
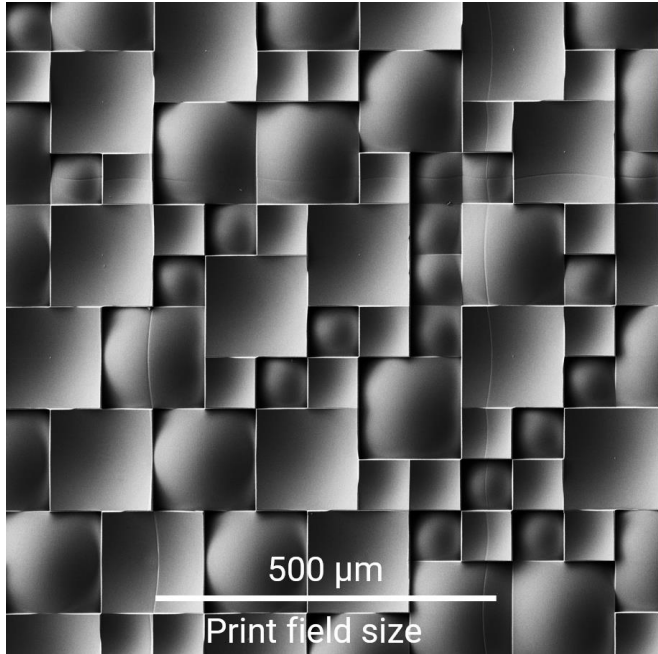
1mm



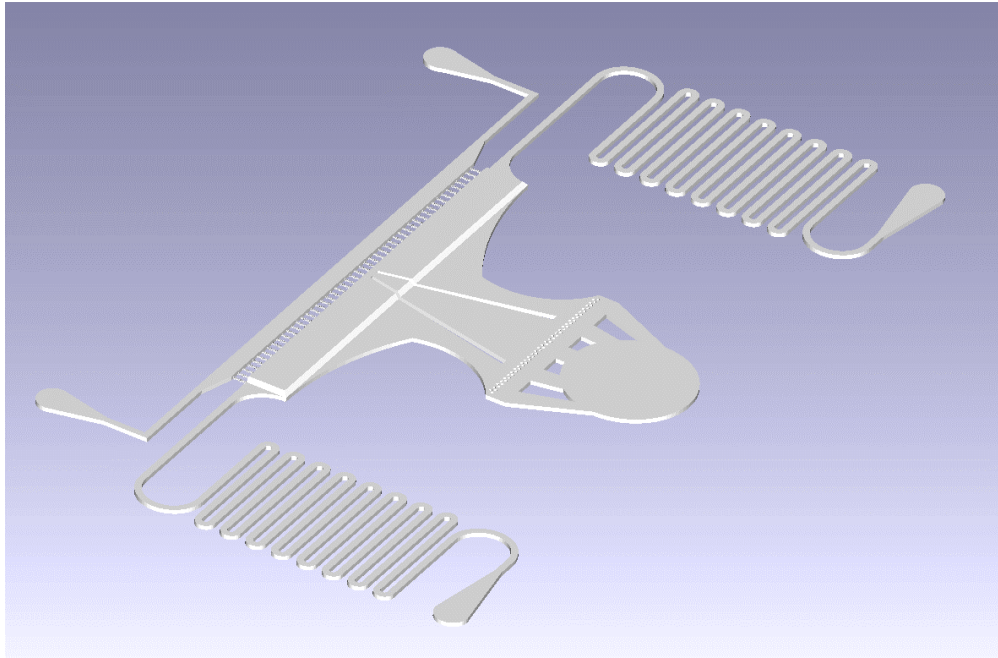
Very uniform patterning  
accuracy over  $5.4 \times 5.4 \text{ mm}^2$



## 2GL tilt-corrected stitching

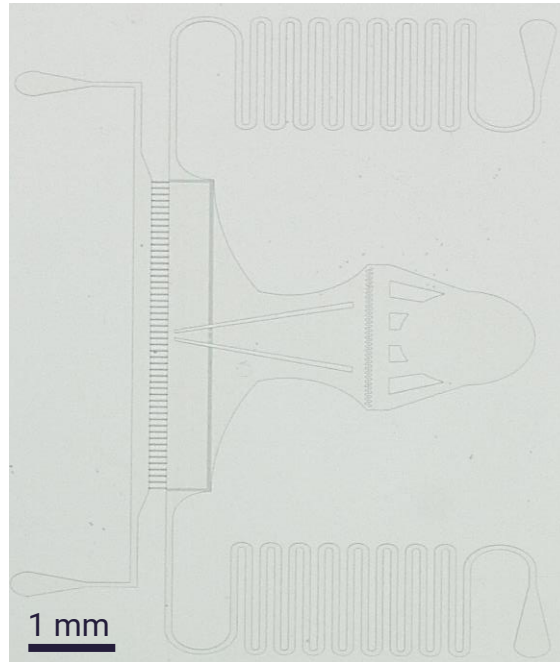


# Microfluidic template by Aachener Verfahrenstechnik, RWTH

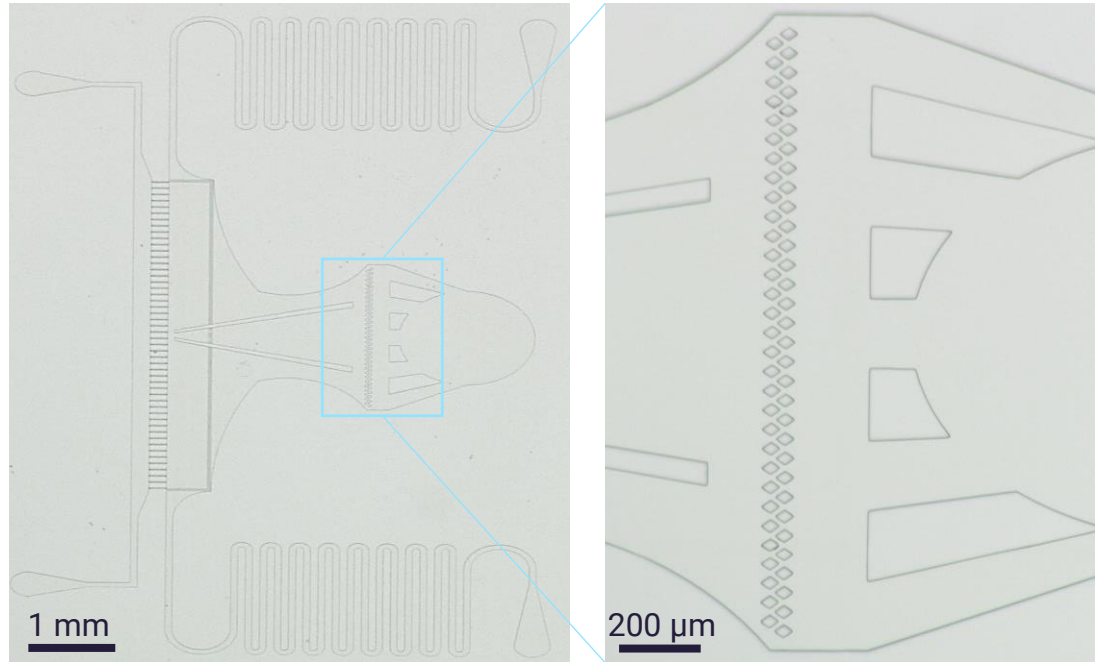


- ▶ Negative polymer template
- ▶ PDMS cast creates microfluidic channel structure
- ▶ Design by AVT, RWTH
- ▶ Printed with Quantum X, 2GL process, with
  - 2GL tilt correction
  - 2GL stitching

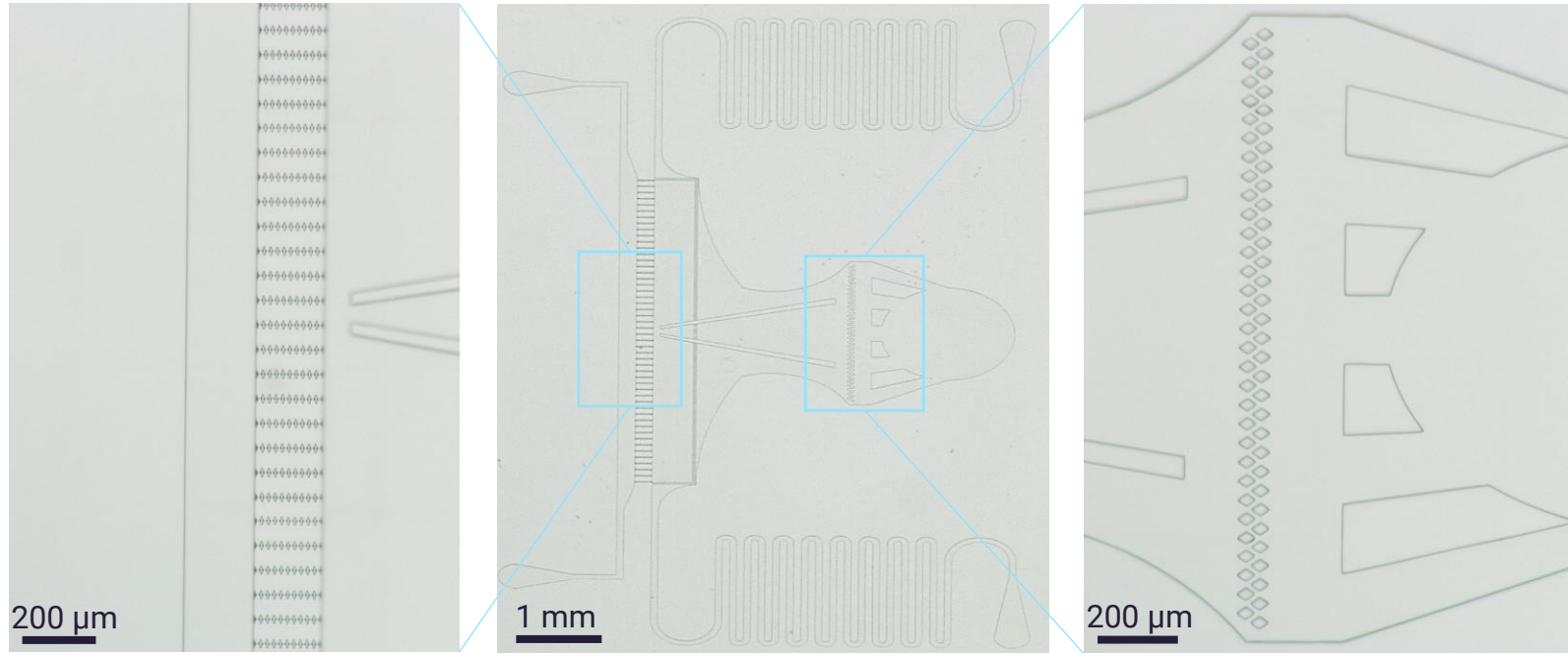
# Microfluidic template by Aachener Verfahrenstechnik, RWTH



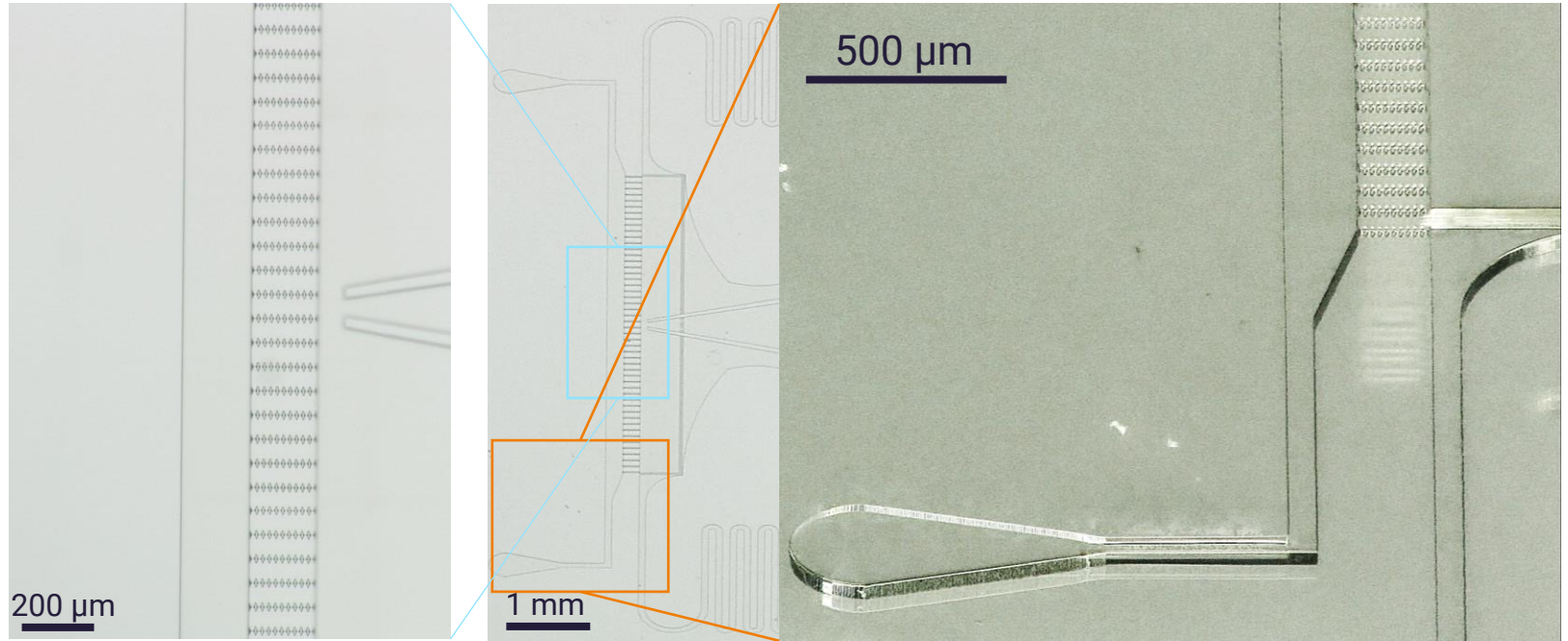
# Microfluidic template by Aachener Verfahrenstechnik, RWTH



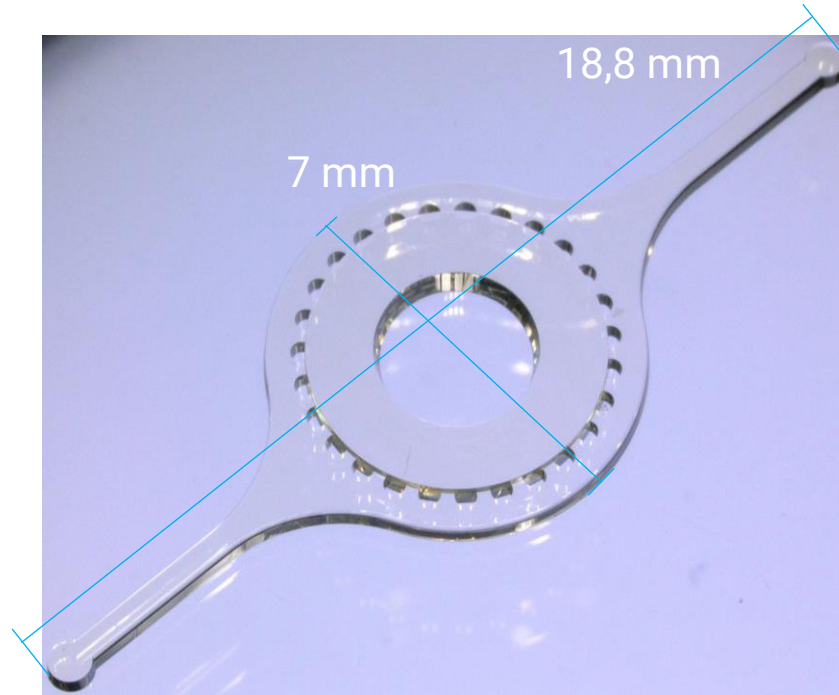
# Microfluidic template by Aachener Verfahrenstechnik, RWTH



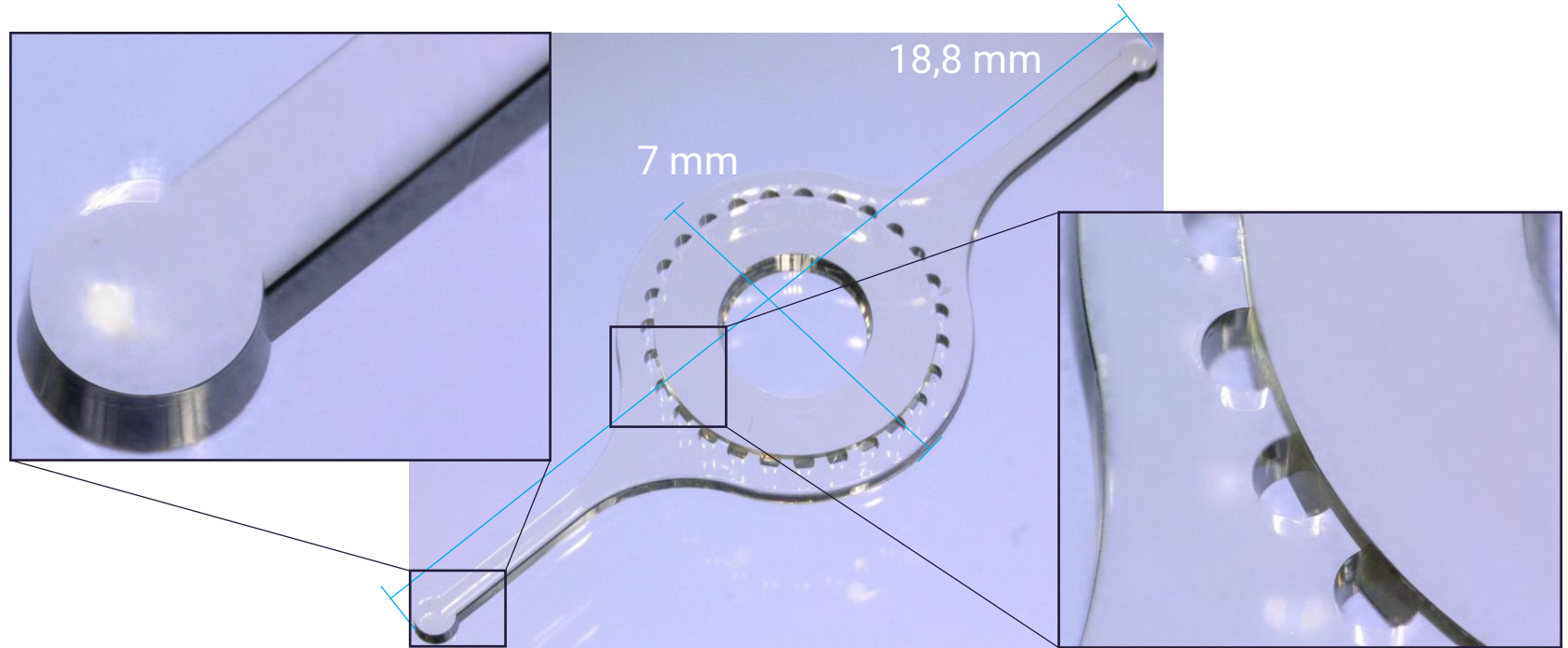
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# Microfluidic template by Aachener Verfahrenstechnik, RWTH



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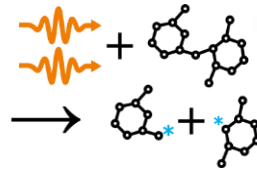
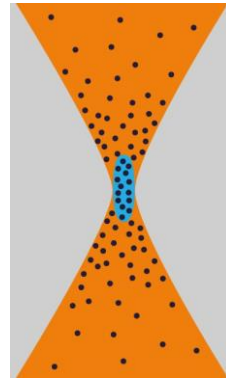




# Summary



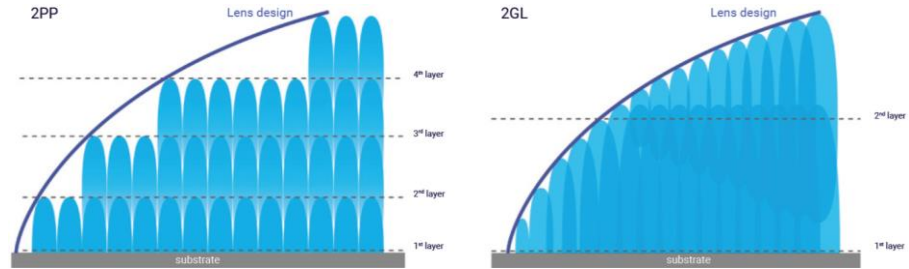
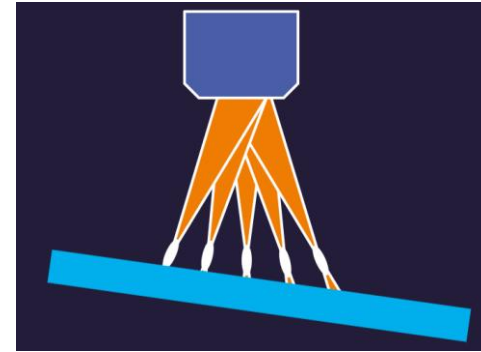
- ▶ Nanoscribe offers 3D microfabrication systems, implementing 2-Photon Polymerization (2PP)



# Summary



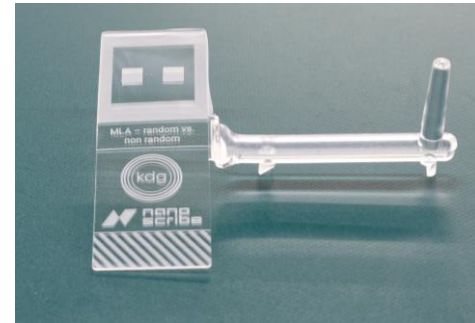
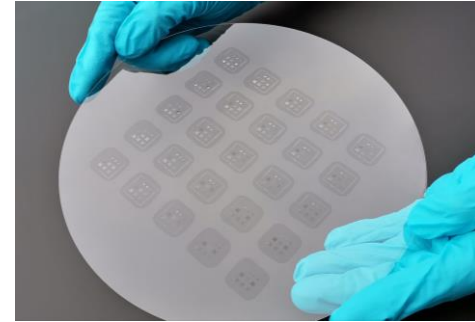
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- ▶ cm-scale smooth 2.5D structures can be printed with Quantum X with 2-Photon Grayscale Lithography (2GL) including tilt correction



# Summary



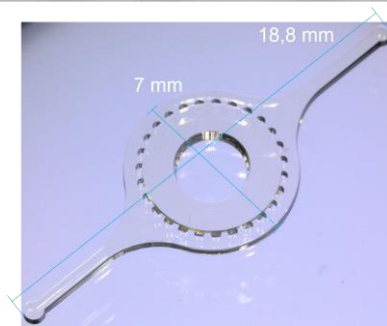
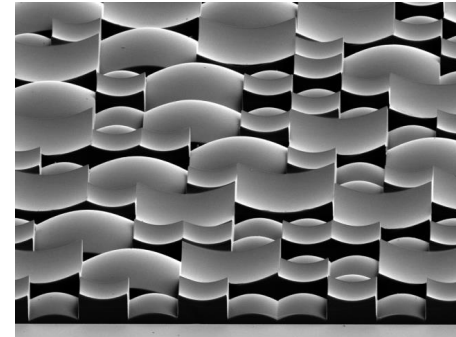
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- ▶ cm-scale smooth 2.5D structures can be printed with Quantum X with 2-Photon Grayscale Lithography (2GL) including tilt correction
- ▶ Printed 2.5D structures can be used as master structures / templates for small and large scale replication



# Summary



- ▶ Nanoscribe offers 3D microfabrication systems, implementing 2-Photon Polymerization (2PP)
- ▶ cm-scale smooth 2.5D structures can be printed with Quantum X with 2-Photon Grayscale Lithography (2GL) including tilt correction
- ▶ Printed 2.5D structures can be used as master structures / templates for small and large scale replication
- ▶ Applications include microoptics and microfluidics





15  
YEARS Think big.  
Print nano.

Think big. Print nano.

Contact us

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